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RESPONSE UNDER 37 CFR 1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 2851

00862.022246

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Kazunori IWAMOTO et al.

Application No.: 09/866,600

Filed: May 30, 2001

For: STAGE APPARATUS WHICH SUPPORTS INTERFEROMETER,)
STAGE POSITION MEASUREMENT METHOD, PROJECTION :
EXPOSURE APPARATUS, PROJECTION EXPOSURE)
APPARATUS MAINTENANCE METHOD SEMICONDUCTOR :
DEVICE MANUFACTURING METHOD, AND)
SEMICONDUCTOR MANUFACTURING FACTORY :

)
: Examiner: H. Nguyen
)

)
: Group Art Unit: 2851
)

)
: Confirmation No.: 4961
)

)
: August 6, 2004
)

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Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

Transmitted herewith is an Amendment in the above-identified application.

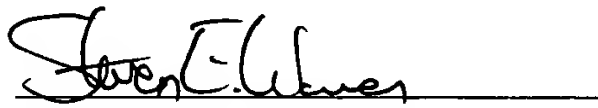
☒ No additional fee is required.

The fee has been calculated as shown below:

CLAIMS AS AMENDED						
	CLAIMS REMAINING AFTER AMENDMENT		HIGHEST NO. PREVIOUSLY PAID FOR	PRESENT EXTRA	RATE	ADDITIONAL FEE
TOTAL CLAIMS	30	MINUS	31	= 0	x \$9 \$18	\$0.00
INDEP. CLAIMS	6	MINUS	7	= 0	x \$43 \$86	\$0.00
Fee for Multiple Dependent claims \$145/\$290						—
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT						\$0.00

- ☐ °Verified Statement claiming small entity status is enclosed, if not filed previously.
- ☐ A check in the amount of \$___ is enclosed including the additional claims fees.
- ☐ Charge \$___ to Deposit Account No. 06-1205. A duplicate of this sheet is enclosed.
- ☒ Any prior general authorization to charge an issue fee under 37 CFR 1.18 to Deposit Account No. 06-1205 is hereby revoked. The Commissioner is hereby authorized to charge any additional fees under 37 CFR 1.16 and 1.17 which may be required during the entire pendency of this application, or to credit any overpayment, to Deposit Account No. 06-1205. A duplicate of this paper is enclosed.
- ☐ A check in the amount of \$___ to cover the fee for a two month extension is enclosed.
- ☐ A check in the amount of \$___ to cover the Information Disclosure Statement fee is enclosed.
- ☒ Applicants' undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should be directed to our address given below.

Respectfully submitted,



Attorney for Applicants
Steven E. Warner
Registration No. 33,326

FITZPATRICK, CELLA, HARPER & SCINTO
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Kazunori IWAMOTO et al.)	: Examiner: H. Nguyen
Application No.: 09/866,600)	: Group Art Unit: 2851
Filed: May 30, 2001)	: Confirmation No.: 4961
For: STAGE APPARATUS WHICH SUPPORTS)	: August 6, 2004
INTERFEROMETER, STAGE POSITION)	:
MEASUREMENT METHOD, PROJECTION)	:
EXPOSURE APPARATUS, PROJECTION)	:
EXPOSURE APPARATUS MAINTENANCE)	:
METHOD, SEMICONDUCTOR DEVICE)	:
MANUFACTURING METHOD, AND)	:
SEMICONDUCTOR MANUFACTURING FACTORY :)	:

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Alexandria, VA 22313-1450

AMENDMENT AFTER FINAL REJECTION

Sir:

In response to the final Official Action dated May 7, 2004, please amend the above-identified application as follows, pursuant to 37 C.F.R. § 1.116: